

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of : Jin Zhao et al. Confirmation No.: 4854  
Application Number : 10/623,757  
Filed : July 21, 2003  
Title : MAINTAINING A REACTOR CHAMBER OF A CHEMICAL  
VAPOR DEPOSITION SYSTEM  
TC/Art Unit : 1792  
Examiner: : Francis P. Smith  
  
Docket No. : TI-35855 (0025.0220)  
Customer No. : **23494**

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**REPLY TO OFFICE ACTION**

In reply to the Office Action mailed October 3, 2008, please amend the  
above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment sections of this paper.